

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Inventor Garo J. Derderian et al.
Assignee Micron Technology, Inc.
Group Art Unit 2812
Examiner Gurley, Lynne Ann
Attorney's Docket No. MI22-2296
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over
Semiconductor Substrates

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

The attached Form PTO/SB/08a is submitted in compliance with 37 C.F.R. §§ 1.56. Pursuant to Federal Register Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. Copies of all other cited art references, if any, are attached. No admission is made regarding whether all the submitted references are prior art. Citation of these references is respectfully requested.

This Supplemental Information Disclosure Statement is being filed after the filing of the Request for Continued Examination (RCE) Application and before receipt of the first Office Action. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated:

January 25, 2007

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